

ABSTRACT

5 A non-contact pad cleaning apparatus that does not cause a liquid to stay on a
polishing surface of a polishing pad and capable of improving a cleaning effect for the
polishing surface is disclosed. The polishing-surface cleaning device includes a plurality
of two-fluid nozzles each configured to eject a two-fluid jet, and an upstream-side nozzle
cover and a downstream-side nozzle cover. The upstream-side nozzle cover is arranged
upstream of the plurality of two-fluid nozzles in a rotation direction of the polishing pad,
10 and the downstream-side nozzle cover is arranged downstream of the plurality of two-fluid
nozzles in the rotation direction of the polishing pad. A distance from the polishing surface
to a lower end of the upstream-side nozzle cover is larger than a distance from the polishing
surface to a lower end of the downstream-side nozzle cover.

15 FIG. 4